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UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Confirmation No.: 7514

Takaei SASAKI et al Group Art Unit: 1746

Serial No.: 10/712,032 Examiner: Michail Kornakov

Filed: November 14, 2003 Attorney Docket No.: 101136-00101

For: METHOD AND APPARATUS FOR DRY-ETCHING HALF-TONE PHASE-SHIFT FILMS, HALF-TONE PHASE-SHIFT PHOTOMASKS AND METHOD FOR THE PREPARATION THEREOF, AND SEMICONDUCTOR CIRCUITS AND METHOD FOR THE FABRICATION THEREOF

AMENDMENT UNDER 37 CFR § 1.111

Mail Stop: AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Date: June 3, 2005

Sir:

In reply to the outstanding Office Action dated March 3, 2005, please amend the above-identified patent application as follows: